



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Y. Long He et al.

Art Unit : 1763

Serial No. : 10/718,832

Examiner : Jeffrie Robert Lund

Filed : November 21, 2003

Title : PLASMA ETCHING UNIFORMITY CONTROL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicants disclose the documents listed on the attached form PTO-1449. Under 37 CFR § 1.98(a)(2)(i), applicants have not provided a copy of the cited U.S. patents.

This statement is being filed after a first Office Action on the merits, but before receipt of a final Office Action or a Notice of Allowance. A check for \$180 in payment of the late submission fee of §1.17(p) is enclosed. Please apply any other charges to deposit account 06-1050, referencing attorney docket 10559-583002.

Respectfully submitted,

Date: 10/15/2004

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*\* See attached document certifying that Rex Huang has limited recognition to practice before the U.S. Patent and Trademark Office under 37 CFR § 10.9(b).*

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CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date of Deposit October 15, 2004

Signature Deborah R. Nast

Typed or Printed Name of Person Signing Certificate  
Deborah R. Nast

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-583002	Application No. 10/718,832
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Y. Long He et al.	
		Filing Date November 21, 2003	Group Art Unit 1763

### U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	5,843,847	12/01/1998	Pu et al.			
	AB	6,436,812	8/20/2002	Lee			
	AC	2002 / 0132488	9/19/2002	Nallan			
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

### Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AJ	61-171127	8/1/1986	Japan (English abstract only)				
	AK							
	AL							
	AM							
	AN							

### Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AO	M. Oda et al. "Xray mask fabrication technology for...". Journal of Vacuum Science & Technology B 14(6):4366-4370, Nov-Dec. 1996.
	AP	P. E. Riley et al. "Implementation of Tungsten Metallization In Multilevel Interconnection Technologies". IEEE Transactions on Semiconductor Manufacturing 3(4): 150-157, November 1990.
	AQ	
	AR	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	